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Dated: November 3, 2003

Signature: 

(Lawrence E. Russ)

Docket No.: INTECH 3.0-087
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Syed Shoaib Hasan Zaidi

Application No.: 10/689,241

Group Art Unit: N/A

Filed: October 20, 2003

Examiner: Not Yet Assigned

For: OPTICAL MEASUREMENT OF DEVICE
FEATURES USING LENSLET ARRAY
ILLUMINATION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

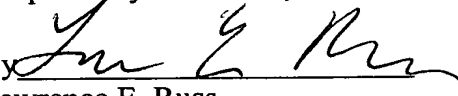
Dear Sir:

It is respectfully requested that the references listed on the enclosed form be made of record and considered with respect to the above-referenced U.S. patent application. Copies non-U.S. Patent references are enclosed. Submission of the present Information Disclosure Statement should not be taken as an admission that the cited references are legally available prior art or that the same are pertinent or material.

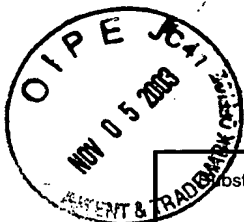
In the event that any fee is due in connection with the present Information Disclosure Statement, the Commissioner is hereby authorized to charge the same to our Deposit Account No. 12-1095.

Dated: November 3, 2003

Respectfully submitted,

By 
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)				Complete if Known	
				Application Number	10/689,241
				Filing Date	October 20, 2003
				First Named Inventor	Syed Shoaib Hasan Zaidi
				Art Unit	N/A
				Examiner Name	Not Yet Assigned
Sheet	1	of	1	Attorney Docket Number	INTECH 3.0-087

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
	AA	US-2003/0063278-A1	04-03-2003	Zaidi	
	AB	US-2003/0133127-A1	07-17-2003	Zaidi, et al.	
	AC	US-6,548,314-B1	04-15-2003	Zaidi	
	AD	US-6,596,377-B1	07-22-2003	Hersee et al.	
	AE	US-6,320,648-B1	11-20-2001	Brueck et al.	
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	AH	US-Re. 36,113-E	02-23-1999	Brueck et al.	
	AI	US-5,759,744-B1	06-02-1998	Brueck et al.	
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	AK	US-5,415,835-B1	05-16-1995	Brueck, et al.	

FOREIGN PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³ -Number ⁴ -Kind Code ⁵ (if known)				

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NON PATENT LITERATURE DOCUMENTS			
Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	CA	Sui, et al., "Integrated Process Control Using an In Situ Sensor for Etch," Solid State Technology, April, 2002	
	CB	Herrick, et al., "Using Broadband Reflectometry for Fast Trench-Depth Measurement," Solid State Technology, February, 2003	
	CC	Logofatu, "Tools for Testing - A Non-Contact, Nondestructive Option for Characterizing Lithography Test Samples, Scatterometry Performance Improves," Spie's OE Magazine, August, 2003, pp. 40-42	
	CD	Seiler, et al., "Challenges of Metrology and Characterization Measurements for ULSI Technology," National Institute of Standards and Technology, pp. 158-166	
	CE	McNeil, "Scatterometry Applied to Microelectronics Processing," www.ieee.org/organizations/pubs/newletters/leos/oct00/scatter.html	
	CF	"The Shack-Hartmann Sensor," www.polytec-pi.fr/wavefrontsciences/opthalmic/hartmannsensor.html	
	CG	"The Shack-Hartmann Sensor," www.wavefrontsciences.com/opthalmic/hartmannsensor.html	

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Examiner Signature		Date Considered	
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